

The Rika™ Source Plasma System may be covered by one or more of the following patents:

Country	Pat. No.
Australia	2018254601
Australia	2022287568
Canada	2024-216396
China	ZL2023300225363
China	CN110709118
China	ZL 2022-11650256.8
Colombia	40710
European Patent Convention	3612248
European Patent Convention	3860677
European Patent Convention	EP3860676
India	458159
Japan	7654053
Japan	7465329
Japan	7723198
Japan	1751385
Japan	1746549
Japan	1751427
Japan	7189150
Mexico	416520
Russian	2807435
Singapore	11201909722W
South Korea	10-2574345
United States	11980707
United States	12357742
United States	11925743
United States	10758664
United States	10758665
United States	D1044029
United States	D1044030
United States	10960128
United States	11013851
United States	12433988
United States	11090425
United States	11103629
United States	11103630
United States	12433989
United States	12377202
United States	11110217
United States	D1092776
United States	12352372
United States	12379916
United States	12478551
United States	12458740
United States	D1021953
United States	D1033455
United States	D1033468
United States	D1048411
United States	12377203
United States	D1081394
Vietnam	40189